

67,200-447; TSMC 00-0890
Serial Number 09/975,855

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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TO: Commissioner for Patents
PO Box 1450
Alexandria, VA 22313-1450

FROM: Tung & Associates
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Bloomfield Hills, MI 48302

DATE: 9 March 2004

REF: Applicant : Hsieh et al. Filing Date : 11 October 2001
Serial No : 09/975,855 Att'y No. : 67,200-447
Art Unit : 1756 Examiner : Saleha R Mohamedulla
Title : Gap Forming Pattern Fracturing Method for Forming Optical
Proximity Corrected Masking Layer

AMENDMENT AND RESPONSE TO OFFICE ACTION MADE FINAL

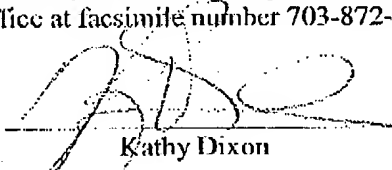
Sir:

In response to an office action mailed on 12 February 2004, please consider the following amendments and remarks pertaining to the above referenced application.

There are no amendments to the specification or drawings. Amendments to the claims are contained within A Listing of the Claims that begins on page 2 of this paper. Remarks begin on page 8 of this paper.

CERTIFICATE OF FACSIMILE TRANSMISSION

I hereby certify that this correspondence is being facsimile transmitted to the United States Patent and Trademark Office at facsimile number 703-872-9311, on April 6, 2004.


Kathy Dixon

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- SRM

- 4/22/04